

Exploring heteroepitaxial growth and electrical properties of α -Ga₂O₃ films on differently oriented sapphire substrates

Wei Wang^{1, 2}, Shudong Hu¹, Zilong Wang¹, Kaisen Liu¹, Jinfu Zhang¹, Simiao Wu¹, Yuxia Yang¹, Ning Xia³, Wenrui Zhang^{1, 4, †}, and Jichun Ye^{1, 4, †}

¹Zhejiang Provincial Engineering Research Center of Energy Optoelectronic Materials and Devices, Ningbo Institute of Materials Technology and Engineering, Chinese Academy of Sciences, Ningbo 315201, China

²The Faculty of Information Science and Engineering, Ningbo University, Ningbo 315211, China

³Zhejiang Provincial Key Laboratory of Power Semiconductor Materials and Devices, ZJU-Hangzhou Global Scientific and Technological Innovation Center, Hangzhou 311200, China

⁴Yongjiang Laboratory, Ningbo 315201, China

Abstract: This study explores the epitaxial relationship and electrical properties of α -Ga₂O₃ thin films deposited on a-plane, m-plane, and r-plane sapphire substrates. We characterize the thin films by X-ray diffraction and Raman spectroscopy, and elucidate thin film epitaxial relationships with the underlying sapphire substrates. The oxygen vacancy concentration of α -Ga₂O₃ thin films on m-plane and r-plane sapphire substrates are higher than α -Ga₂O₃ thin film on a-plane sapphire substrates. All three thin films have a high transmission of over 80% in the visible and near-ultraviolet regions, and their optical bandgaps stay around 5.02–5.16 eV. Hall measurements show that the α -Ga₂O₃ thin film grown on r-plane sapphire has the highest conductivity of 2.71 S/cm, which is at least 90 times higher than the film on a-plane sapphire. A similar orientation-dependence is seen in their activation energy as revealed by temperature-dependent conductivity measurements, with 0.266, 0.079, and 0.075 eV for the film on a-, m-, r-plane, respectively. The origin of the distinct transport behavior of films on differently oriented substrates is suggested to relate with the distinct evolution of oxygen vacancies at differently oriented substrates. This study provides insights for the substrate selection when growing α -Ga₂O₃ films with tunable transport properties.

Key words: gallium oxide; thin film epitaxy; orientation; oxygen vacancy; electrical properties

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1. Introduction

As an emerging third-generation semiconductor material, gallium oxide (Ga₂O₃) has superior properties such as wide band gap, high breakdown electric field, and strong radiation resistance, which can more effectively serve the emerging needs of power electronic device development, such as Schottky barrier diodes (SBDs)^[1, 2], heterojunction diodes^[3, 4], metal-oxide semiconductor field-effect transistors (MOSFETs)^[5, 6], etc. compared with Si, SiC and GaN^[5, 7–9]. It has a wide range of application prospects in the field of advanced information technology and new energy.

Ga₂O₃ has five crystalline phases: α , β , δ , γ and ϵ . Among them, the monoclinic structure β -Ga₂O₃ is a thermally stable phase at high temperature, and the other four phases are all metastable crystalline phases^[10–16]. But, due to the lack of symmetry of monoclinic β -Ga₂O₃ compared with the hexagonal system, there is a problem of "twisting" in the heteroepitaxial, which is a major difficulty in the crystal quality of heteroepitaxial thin films^[17]. Compared with β -Ga₂O₃, the corundum structure α -Ga₂O₃ is one of the metastable phases and has a wider

band gap and higher breakdown field strength, making it more suitable for the fabrication of power electronic devices^[18]. Both α -Ga₂O₃ ($a = 4.98 \text{ \AA}$, $c = 13.43 \text{ \AA}$)^[19] and sapphire ($a = 4.76 \text{ \AA}$, $c = 12.99 \text{ \AA}$) (PDF: 46-1212) belong to a corundum structure, and the lattice mismatch between them is small. Therefore, sapphire is well suited as a substrate for epitaxial α -Ga₂O₃. We have mainly selected sapphire substrates with three different crystal orientations: a-plane (11 $\bar{2}$ 0), m-plane (10 $\bar{1}$ 0) and r-plane (01 $\bar{1}$ 2). The study of the electrical properties of α -Ga₂O₃ thin films is an important basis for the fabrication of high-performance devices. However, the effect of substrate crystal orientation on the thin film properties remains contentious, including the crystalline quality and the electrical properties of the thin films^[7, 20–23]. The anisotropy of the electrical properties of Ga₂O₃ may be follows from the anisotropy of the long-range electron–phonon interaction, as well as from the conduction band anisotropy^[24]. On the other hand, the defects also play a crucial role in the electrical properties^[25]. Therefore, there is a significant need to investigate the effect of substrate crystal orientation on the heteroepitaxial and electrical properties of the films.

The main methods currently used to grow Ga₂O₃ films are radio frequency magnetron sputtering (RFMS)^[25, 26], metal organic chemical vapor deposition (MOCVD)^[14, 27–29], molecular beam epitaxy (MBE)^[7, 8]. Compared to the above methods, pulsed laser deposition (PLD) has the following outstanding

Correspondence to: W R Zhang, zhangwenrui@nimte.ac.cn; J C Ye, jichun.ye@nimte.ac.cn

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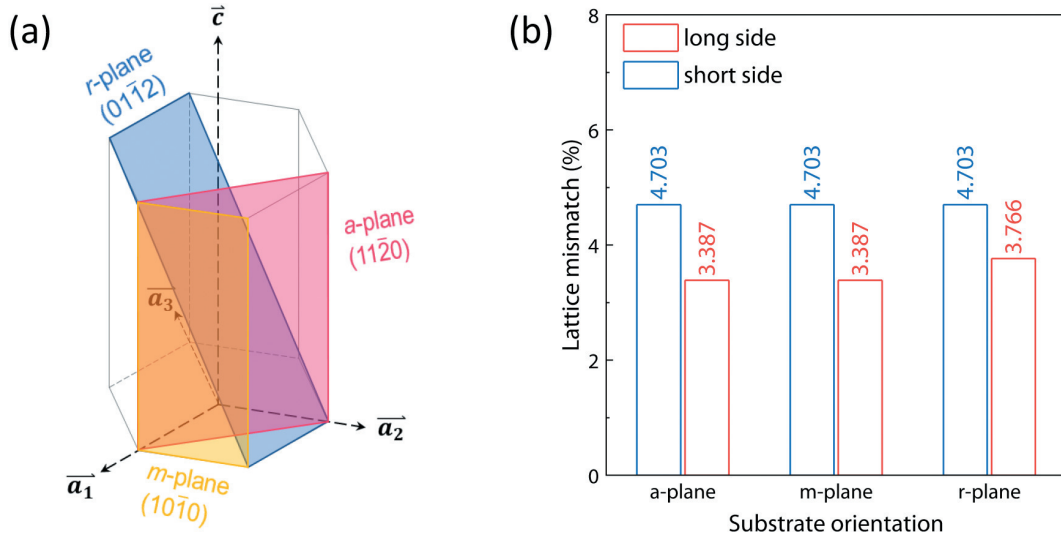


Fig. 1. (Color online) (a) Schematic diagram of various crystal planes in the corundum structure. (b) The lattice mismatch between different crystal planes α -Ga₂O₃ films and corresponding sapphire substrates.

advantages: fast film growth, easy doping, easy preparation of films with the same stoichiometric ratio as the target, easy adjustment of the growth process^[10, 11, 13, 30].

In this work, we have systematically investigated the epitaxial relationships and the differences in electrical properties of epitaxial α -Ga₂O₃ films on a-plane, m-plane, and r-plane sapphire substrates using the PLD technique. We found that the epitaxial films have the same corundum structure and the growth orientation as the substrate, respectively. The conductivity shows an increasing trend from a-plane to m-plane to r-plane, which may be related to oxygen vacancy.

2. Experimental

The 1% Sn-doped α -Ga₂O₃ thin films were deposited with the same growth condition on a-plane, m-plane, and r-plane sapphire substrates by PLD (SKY Technology Development Co., Ltd. Chinese Academy of Sciences), at about 800 °C, the oxygen pressure was fixed at 0.1 mTorr. The epitaxial growth relationship and crystalline structure of α -Ga₂O₃ film were analyzed by X-ray diffraction (XRD, D8 Discover). The structure of the α -Ga₂O₃ thin films was also confirmed by Raman spectroscopy (Renishaw inVia Reflex) at room temperature using a laser beam of 532 nm. Film transmission in the range of 200–800 nm was measured by a UV-visible spectrophotometer (UV-vis, Lambda 1050). The elemental composition and chemical state were characterized by X-ray photoelectron spectroscopy (XPS, Kratos AXIS SUPRA) using Mg K α ($h\nu = 1253.6$ eV) as the excitation source. The electrode spacing and effective electrode area were controlled using a direct-write optical lithography machine (MicroWriter ML3) and a lift-off process. The electrical properties at room temperature and various temperatures were measured in the Hall measurement system (HL-5500PC) with a 0.5 T magnet, and in a semiconductor parameter analyzer (Keithley 4200-SCS), respectively.

3. Results and discussion

The schematic diagram of different crystal planes in the corundum structure are shown in Fig. 1(a). The lattice mis-

match (δ) is calculated according to the following equation: $\delta = (a_e - a_s)/a_s$. Here, a_e and a_s indicate the lattice constants of epitaxial thin films and substrates, respectively. The lattice mismatches between different crystal planes α -Ga₂O₃ films and corresponding sapphire substrates are shown in Fig. 1(b). It is easy to find that the lattice mismatch between r-plane sapphire and r-plane α -Ga₂O₃ of the long side is larger than that of the a-plane and m-plane, which may be the reason why it is more difficult to epitaxy Ga₂O₃ on r-plane sapphire.

We determine the crystalline phase of Ga₂O₃ using XRD and Raman scattering. As shown in Fig. 2(a), the (11̄20) and (22̄40) diffraction peaks of α -Ga₂O₃ are accompanied by (11̄20) and (22̄40) diffraction peaks of a-plane sapphire, the (30̄30) diffraction peak of α -Ga₂O₃ are accompanied by (30̄30) diffraction peak of m-plane sapphire, and the (011̄2), (02̄24) and (03̄36) diffraction peaks of α -Ga₂O₃ are accompanied by (011̄2), (02̄24) and (03̄36) diffraction peaks of r-plane sapphire. The structure of α -Ga₂O₃ thin films is also confirmed by Raman scattering. The XRD θ -2 θ scan patterns of the above three samples all show that the crystal orientation of the α -Ga₂O₃ films is almost consistent with the sapphire substrate.

XRD ϕ -scan mode measurements are used to further determine the in-plane epitaxial growth relationship of α -Ga₂O₃ film relative to sapphire substrates. As shown in Fig. 2(b), the characteristic (30̄30) of a-plane α -Ga₂O₃ thin film and (30̄30) of a-plane sapphire substrate appear at the same rotational angle of ϕ , suggesting that the α -Ga₂O₃ thin film has the same corundum structure as the sapphire substrate. The (02̄24) of the m-plane α -Ga₂O₃ thin film and sapphire substrate, and the (011̄2) of r-plane α -Ga₂O₃ thin film and sapphire substrate show similar results to those above.

Fig. 2(c) shows the Raman shift of α -Ga₂O₃ thin films grown on a-, m-, r-plane sapphire substrates. The Raman peaks belonging to α -Ga₂O₃ thin film are mainly located at 430.4, 575.8 cm⁻¹, which is consistent with reported values^[31, 32]. The Raman results are consistent with the XRD results. The XRD rocking curves of a-plane α -Ga₂O₃ (1120) peak, m-plane α -Ga₂O₃ (3030) peak, and r-plane α -Ga₂O₃ (0224) peak are shown in Fig. 2(d). The fullwidth at half maxi-

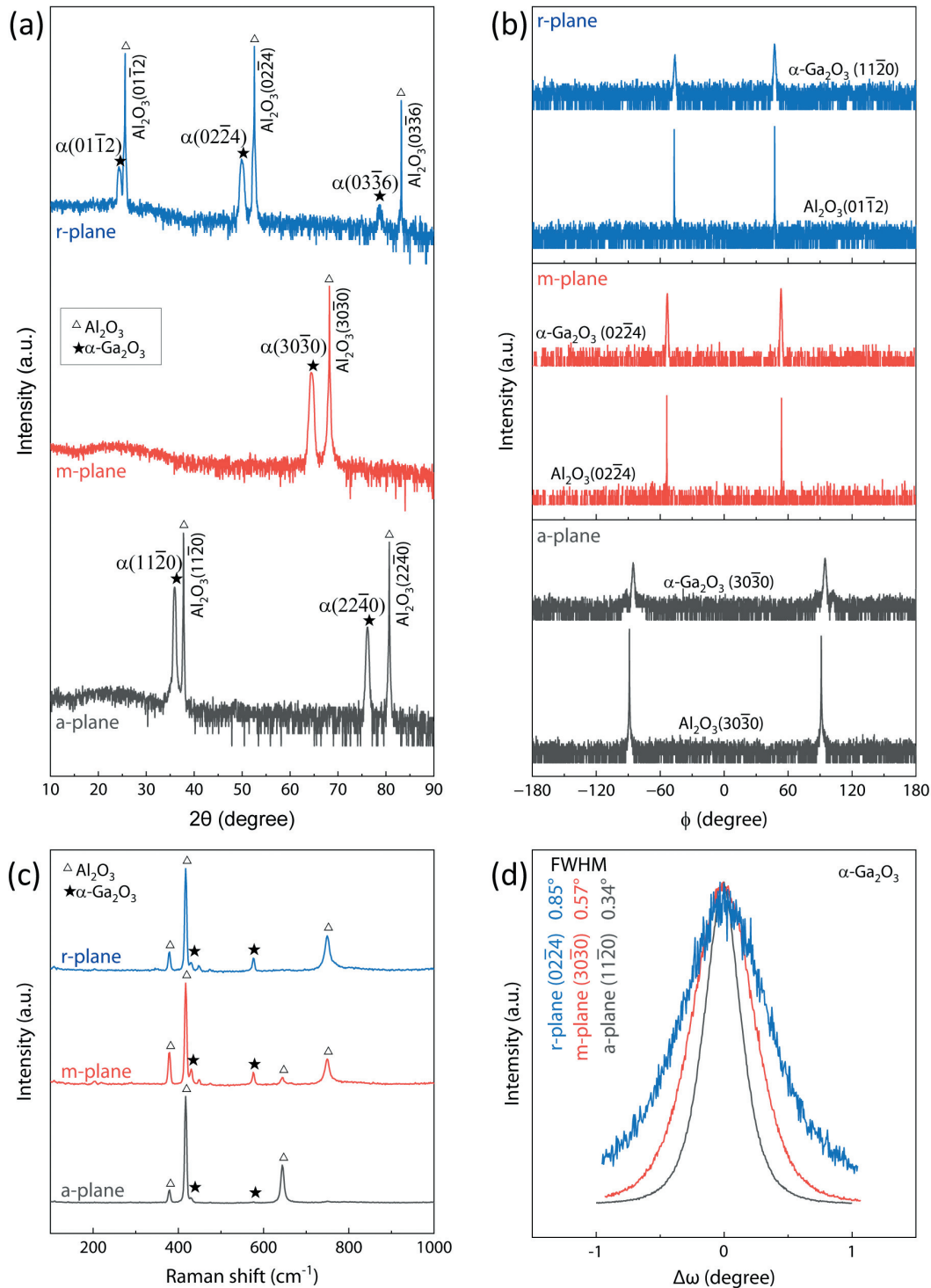


Fig. 2. (Color online) (a) XRD θ - 2θ full scans of α -Ga₂O₃ thin films grown on a-plane, m-plane, and r-plane sapphire substrates. (b) XRD ϕ -scans of (30 $\bar{3}$ 0) plane, (02 $\bar{2}$ 4) plane, and (11 $\bar{2}$ 0) plane of corresponding α -Ga₂O₃ films and the underlying sapphire, respectively. (c) Raman scattering spectra of α -Ga₂O₃ thin films grown on a-plane, m-plane, and r-plane sapphire substrates. (d) XRD rocking curves around the α -Ga₂O₃ (11 $\bar{2}$ 0) peak grown on a-plane sapphire, α -Ga₂O₃ (30 $\bar{3}$ 0) peak grown on m-plane sapphire, and α -Ga₂O₃ (02 $\bar{2}$ 4) peak grown on r-plane sapphire.

mum (FWHM) of the ω -scan rocking curves of (11 $\bar{2}$ 0) peak, (30 $\bar{3}$ 0) peak, and (02 $\bar{2}$ 4) peak are 0.34°, 0.57°, and 0.85°, respectively. This indicates that the crystalline quality of a-plane α -Ga₂O₃ is greater at the a-plane than m-plane and r-plane, which is affected by multiple factors, including the different crystalline quality of the substrate with different orientations, the lattice mismatch, and the nucleation kinetics for different orientations^[17, 33, 34].

Based on the above test results, it is not difficult to

deduce the growth behaviors of α -Ga₂O₃ thin films grown on differently-oriented sapphire substrates. As shown in Fig. 3, the unit cell arrangement of α -Ga₂O₃ thin films is almost the same as that of the corresponding sapphire substrates.

Then, we probed the defect density and distribution of differently-oriented α -Ga₂O₃ films using XPS. Fig. 4 shows the O 1s core level spectra of various plane α -Ga₂O₃ thin films. We calibrate the data with a standard binding energy of 284.8 eV for the C 1s peak^[35]. The XPS O 1s core level spectra of the films

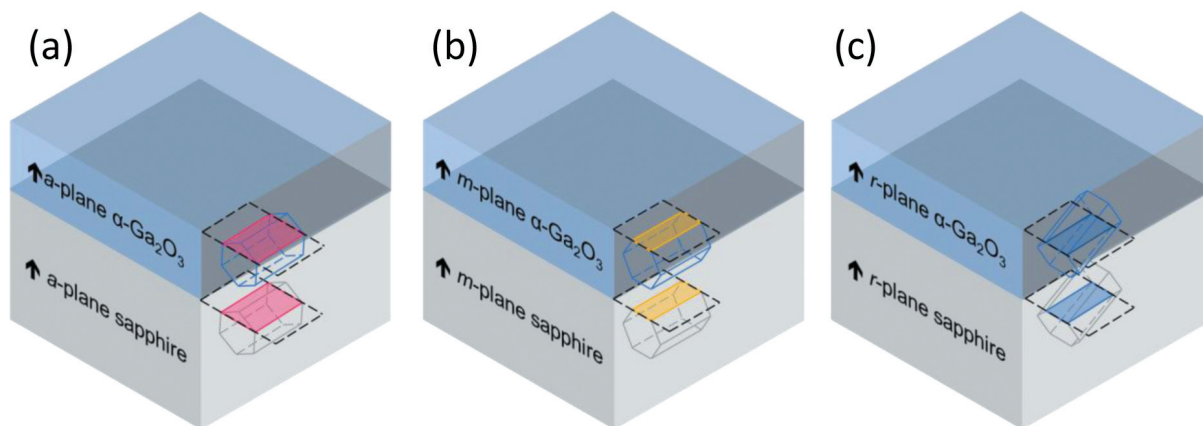


Fig. 3. (Color online) Schematic of growth relation of α -Ga₂O₃ grown on (a) a-plane, (b) m-plane, and (c) r-plane sapphire substrates by PLD.

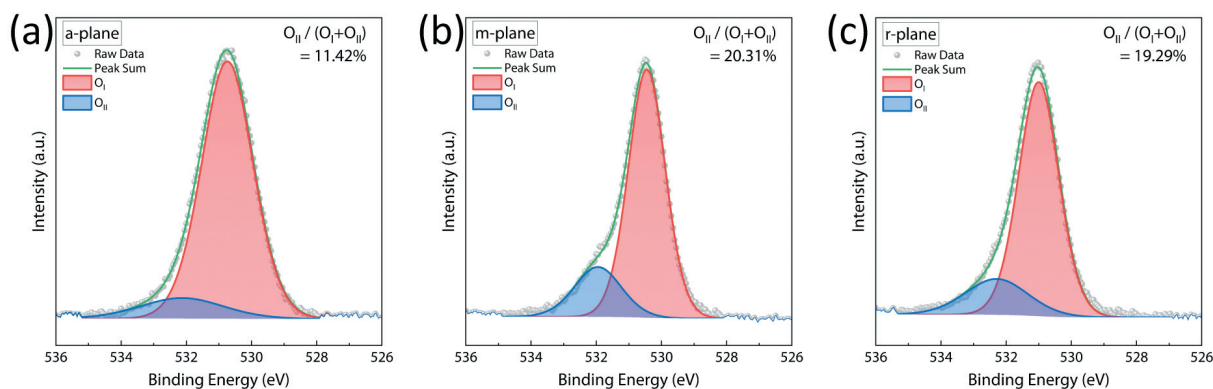


Fig. 4. (Color online) XPS spectra of O 1s peak of α -Ga₂O₃ films grown on (a) a-plane, (b) m-plane, and (c) r-plane sapphire substrates.

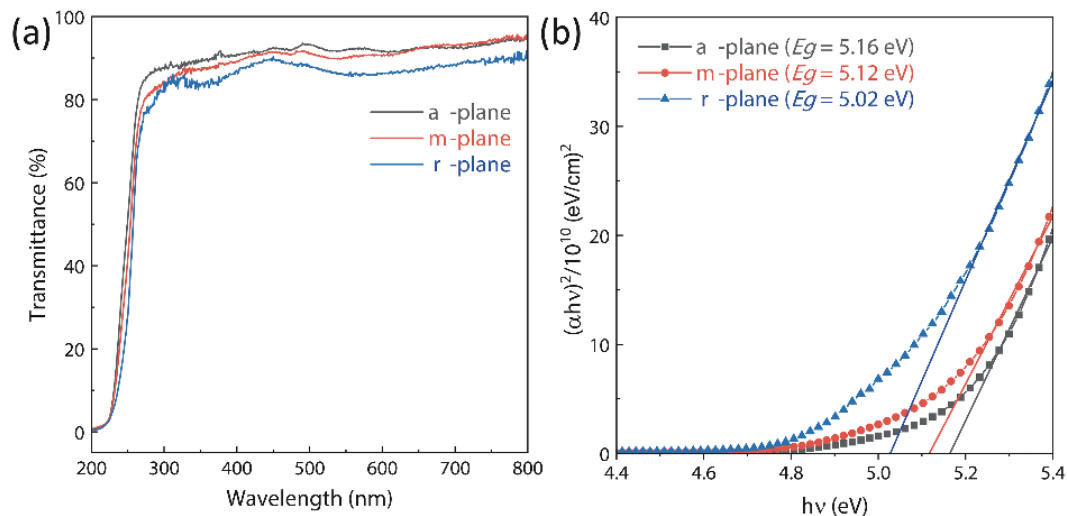


Fig. 5. (Color online) (a) Transmittance spectra and (b) Tauc plot of the a-plane, m-plane, and r-plane α -Ga₂O₃ thin films grown on various plane sapphire substrates.

are divided into two individual peaks and well fitted with the sum Gaussian functions. The positions of the two peaks correspond to lattice oxygen of Ga₂O₃ (O_I) and oxygen vacancies (O_{II}), respectively^[26]. We can use $O_{II}/(O_I+O_{II})$ to reflect the concentration of oxygen vacancies. The oxygen vacancy concentration of the a-plane, m-plane, and r-plane α -Ga₂O₃ are 11.42%, 20.31%, and 19.29%, respectively.

Furthermore, the UV-vis transmission spectra for as grown α -Ga₂O₃ epitaxial films on differently-oriented sapphires are illustrated in Fig. 5(a). Both films have high trans-

parency (>80%) in the visible and near-UV regions. As shown in Fig. 5(b), the optical band gap (E_g) of the α -Ga₂O₃ films can be evaluated using the plot of $(\alpha hv)^2$ vs hv , where α is the absorption coefficient and hv is the photon energy. a-plane, m-plane, and r-plane α -Ga₂O₃ films have an estimated bandgap of 5.16, 5.12, and 5.02 eV, respectively.

In order to explore the electrical transport properties of differently-oriented α -Ga₂O₃ thin films, Hall measurement is performed in a conventional van der Pauw geometry. Table 1 shows the results of Hall measurements. The conductivity (σ)

Table 1. Film thicknesses, conductivities, mobilities, and carrier concentrations for α -Ga₂O₃ thin films grown on a-, c- and r-plane sapphire substrates.

Substrate	Thickness (nm)	σ (S/cm)	μ (cm ² /(V·s))	n (10 ¹⁷ cm ⁻³)
a-sapphire	302	Exceed test limit (<0.03)	–	–
m-sapphire	280	0.29	12.2	1.45
r-sapphire	273	2.71	1.35	125

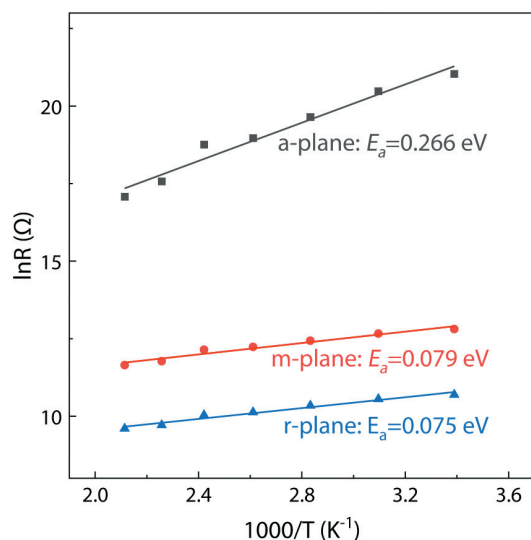


Fig. 6. (Color online) Fitting plots of temperature-dependent resistance deriving the activation energy for a-plane, m-plane, and r-plane α -Ga₂O₃ thin films.

of the α -Ga₂O₃ thin film epitaxial on a-plane sapphire exceeds the measurement capacity of the Hall tester. For α -Ga₂O₃ thin film epitaxial on m-plane sapphire, Hall measurements indicate that the film is n-type conductive with a high conductivity of 0.29 S/cm, a mobility (μ) of 12.2 cm²/(V·s) and a carrier concentration (n) of 1.45×10^{17} cm⁻³. While the α -Ga₂O₃ thin film epitaxial on r-plane sapphire has a higher conductivity of 2.71 S/cm, a mobility of 1.35 cm²/(V·s) and a high carrier concentration of 1.25×10^{19} cm⁻³.

The temperature dependence of the resistance in the range from 295 to 473 K for the Sn-doped α -Ga₂O₃ thin films are shown in Fig. 6. The activation energy (E_a) is derived from the linear fit of the $\ln(R)-T$ plot using $R \propto \exp(E_a/k_B T)$, where R is the resistance, k_B is the Boltzmann constant, and T is the temperature^[10, 36]. The estimated activation energy for α -Ga₂O₃ epitaxial on a-plane, m-plane and r-plane sapphire substrates are 0.266, 0.079, and 0.075 eV, respectively. The value of activation energy is used to quantify the thermal ionization of defect states^[28].

The α -Ga₂O₃ thin films on m-plane and r-plane sapphire substrates are far more conducting than α -Ga₂O₃ thin film on a-plane sapphire substrate under similar thin film growth conditions. It is interesting that the oxygen vacancy concentration of α -Ga₂O₃ thin films on m-plane and r-plane sapphire substrates are also higher than α -Ga₂O₃ thin film on a-plane sapphire substrates. It is speculated that the conductivity behavior of α -Ga₂O₃ thin films may be related to the oxygen vacancy concentration, and the formation energy could strongly depend on the lattice orientation, thus leading to drastical differences in the dopant activation and carrier transport^[29, 37, 38]. Further studies on the mechanism of the effect

of anisotropy and crystallinity on electrical conductivity are expected.

4. Conclusions

We have investigated the Sn-doped α -Ga₂O₃ thin films deposited on a-plane, m-plane, and r-plane sapphire substrates by PLD. Due to the same corundum structure, the out-of-plane and in-plane alignment of α -Ga₂O₃ films is almost identical to that of the corresponding oriented sapphire substrate. The FWHMs of ω -scan rocking curves of the a-plane, m-plane, and r-plane α -Ga₂O₃ thin films are 0.34°, 0.57°, and 0.85°, respectively. The r-plane α -Ga₂O₃ thin film has the highest conductivity, the m-plane α -Ga₂O₃ thin film the second, and the a-plane α -Ga₂O₃ thin film dramatically more insulating. A similar trend is also observed in their activation energy. This could be understood by that the orientation difference leads to the concentration variation of oxygen defects in differently oriented α -Ga₂O₃ thin films, further causing differences in the electrical properties of the thin films.

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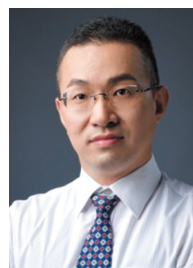
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Wei Wang is a M.S. candidate under the supervision of Dr. Wenrui Zhang at Ningbo Institute of Materials Technology and Engineering, Chinese Academy of Sciences. His research focuses on gallium oxide thin film growth and electronic devices.



Wenrui Zhang received his Ph.D. degree at Texas A&M University in 2015. He is a professor at Ningbo Institute of Materials Technology and Engineering, Chinese Academy of Sciences. His research interest is wide bandgap semiconductors and microelectronic devices.



Jichun Ye received his Ph.D. degree at University of California, Davis in 2005. He is a professor and the deputy director of the Institute of New Energy Technology affiliated with Ningbo Institute of Materials Technology and Engineering, Chinese Academy of Sciences. His main research areas include the development of solar cells and wide bandgap semiconductors.